

Notice of References Cited		Application/Control No.	Applicant(s)/Patent Under Reexamination USAMI, TATSUYA	
		Examiner Julio J. Maldonado	Art Unit 2823	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	C	US-6,218,317 B1	04-2001	Allada et al.	438/780
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	L	US-			
	M	US-			

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
*	U	Wolf et al., Silicon Processing for the VLSI Era, Volume 1-Process Technology, 1986, Lattice Press, pages 168-174.
*	V	Chen et al., Effects of slurry formulations on chemical-mechanical polishing of low dielectric constant polysiloxanes: hydrido-organo siloxane and methyl silsesquioxane; J. Vac. Sci Technol. B 18(1), Jan/Feb 2000; pages 201-207
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.